

<b>Notice of References Cited</b>	Application/Control No. 09/916,381	Applicant(s)/Patent Under Reexamination HAGA ET AL.	
	Examiner Lynette T. Umez-Eronini	Art Unit 1765	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	JP 11194120	08-1998	JAPAN	Satoro et al.	G01N 31/12
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Satoro, Method and Apparatus for Quantitative Analysis of Mixed Acid Solution in Etching Process As Well As Etching Control Method and Preparation of the Mixed Acid Solution, August 6, 1998, English translation by computer for JP 11194120, 9 pages.
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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